### Model IR-2200

# SEIWA Infrared Microscope System



IR-2200 Microscope System enable the user to inspect sub-surface images including MEMS device, 3D stacks, incoming wafers, photovoltaic, and wafer level CSP's with an astonishing level of precision, while offering many capabilities and flexibility not available with traditional microscopes.



## Model IR-2200

The IR-2200 system integrates the infrared table top microscope system with software and 4.1 Megapixel USB-3.0 NIR Camera. This system provides all necessary features for high precision measurements, image capture, verification and inspection of materials transparent to the near infrared (NIR) / Shortwave Infrared (SWIR) wavelengths.

#### **Specifications**

Model	IR-2200	Illumination	Koehler illumination
Spectral sensitivity range Objective lens	400nm - 2000nm Selection from Seiwa M.Plan APO and PE IR Plan series	Turret	4 nose manual turret
		Stand	Coarse / fine Z focus
		Stage	Coarse manual XY stage. (Other option is available upon request)
		Camera	Cooled Ingaas camera (900nm-1700nm)
			Silicon based option for NIR application (740nm-1100nm)

#### Seiwa M.Plan APO Series: Spectral sensitivity range from 400nm - 1100nm

Model	M.Plan APO	M.Plan APO	M.Plan APO	M.Plan APO
Magnification	2.5 X	5X	10X	20X
Working Distance	32.0mm	35.1mm	36.9mm	22.0mm
Focal Distance	80.0mm	40mm	20mm	10mm
NA	0.06	0.15	0.25	0.4
Resolution	<b>4.6</b> μm	1.7 μm	1.2 μm	0.8 μm
Focal Depth	76.4 μm	10.7 µm	4.4 μm	2.2 μm
Wavelength	0.4-1.1 μm	0.4-1.1 μm	0.4 <b>-</b> 1.1 μm	0.4-1.1 μm

\*the resolution is calculated as a theoretical resolution based on NA of wavelength 550nm

#### Seiwa PE IR Plan Series : Spectral Sensitivity range from 900nm - 2000nm

Model	PEIR1X	PEIR2.5X	PEIR10X	PEIR20X	PEIR50X	PEIR100X	PEIR20X 2000HR	PEIR50X 2000HR
Magnification	1.0 X	2.5 X	10 X	20 X	50 X	100	20 X	50 X
Working Distance	12mm	28.0mm	30.7mm	12mm	10mm	10mm	10mm	10mm
Focal Distance	200mm	80mm	20mm	10mm	4mm	2mm	10mm	4mm
NA	0.03	0.1	0.27	0.5	0.6	0.75	0.6	0.71
Resolution	18.4 μm	0.3 µm	2.5 μm	1.1 µm	0.9 µm	0.7 µm	1.5 μm	1.2 µm
Focal Depth	611 µm	55 µm	7.5 μm	2.2 μm	1.5 µm	0.9 µm	2.15 µm	1.58 µm
Wavelength	0.8-1.6 µm	0.45-1.6 µm	0.48-1.6 µm	0.8-1.6 μm	0.9 <b>-1</b> .6 µm	0.9 <b>-</b> 1.6 µm	1-2 µm	1-2 µm

\*The resolution is calculated as a theoretical resolution based on NA of wavelength 1100nm

\*PEIR2000HR lens theoretical resolution based on NA of wavelength of 1550nm

#### **DataSheet SWIR Camera Series**

The IK1523 camera is a highly sensitive infrared camera (SWIR, NIR). The sensitivity interval reaches from 900 nm to 1700 nm.

A sophisticated, thermal optimized housing allows sensor operation without active cooling. The optional available M42 or F - mount to C - mount adapter extends the number of lenses which can be used with this camera. Via standard USB2.0 interface can be controlled by each PC or notebook.



Model	IK1513	IK1523
Sensor Size	3/4" InGaAs matrix sensor, progrssive scan	1/3" InGaAs matrix sensor, progrssive scan
Resolution	320 (H) x 256 (V) pixels	640 (H) x 512 (V) pixels
Pixel Size	30 µm x 30 µm	25 μm x 25 μm
Spectral Range	0.9 µm to 1.7 µm	0.9 µm to 1.7 µm
Active Sensor Size	9.6mm (H) x 7.68mm (V)	16mm (H) x 12.8mm (V)
A/D Resolution	14 bit	14 bit
Frame Rate	110 fps	30 fps
Exposure Time	35 µs to 1 s	67 µs to 1 s

NOTE: for more information and specifications, please view our cameras catalogue



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